

WHAT IS CLAIMED IS:

1. A conveyor device for a flexible substrate, said conveyor device comprising:
a conveying means for continuously conveying a flexible substrate from one end to the other end;
5 a plurality of cylindrical rollers being provided between the one end and the other end along an arc with a radius R;
sub 7 wherein center axes of the plurality of cylindrical rollers run parallel to each other; and
a mechanism for conveying the flexible substrate while the substrate is
10 in contact with each of the plurality of cylindrical rollers.

2. A device according to claim 1,
wherein the radius R of the arc is in a range of 0.5 to 10 m.

3. A film formation apparatus for a flexible substrate, said film formation apparatus comprising:
15 a conveying means for continuously conveying a flexible substrate from one end to the other end;
a plurality of cylindrical rollers being provided between the one end and the other end along an arc with a radius R;
sub 20 wherein center axes of the plurality of cylindrical rollers run parallel to each other; and
a mechanism for conveying the flexible substrate while the substrate is in contact with each of the plurality of cylindrical rollers.

4. An apparatus according to claim 3,
wherein the radius R of the arc is in a range of 0.5 to 10 m.

5. An apparatus according to claim 3 further comprising:

a vacuum chamber;

5 an introducing means for introducing a gas into the vacuum chamber;

a gas evacuation means; and

an energy supplying means for supplying an energy to make a plasma
from the gas.

6. An apparatus according to claim 3,

10 wherein the film formation apparatus is a plasma CVD apparatus.

7. An apparatus according to claim 5,

wherein the energy is an electromagnetic wave.

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